DESCRIPTION

PLANT CULTIVATION ~~DEVICE~~APPARATUS

TECHNICAL FIELD

[0001]

The present technology relates to a plant cultivation apparatus used in a factory for cultivating vegetables or other plants.

BACKGROUND ART

[0002]

PTL 1 discloses a technology relating to a plant cultivation facility. The plant cultivation facility disclosed in PTL 1 includes a cultivation bed where plants are cultivated, a cultivation panel which includes a plurality of vent holes formed in a thickness direction of the panel, and overlaps with the cultivation bed on the side above the bed with a clearance left between the panel and the bed, and an air conditioning mechanism which introduces gas into the clearance between the cultivation bed and the cultivation panel.

Citation List

Patent Literature

[0003]

PTL 1: Unexamined Japanese Patent Publication No. 2012-28

SUMMARY OF THE INVENTION

[0004]

A plant cultivation apparatus according to the present technology includes a cultivation space where a cultivation environment is controllable,